

# Process, Device, and Modeling

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- Device Models
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  - Small signal model
- Comparison of BJT & MOSFET
  - Transconductance
  - Intrinsic gain
  - Frequency response
  - Matching
  - Other parameters

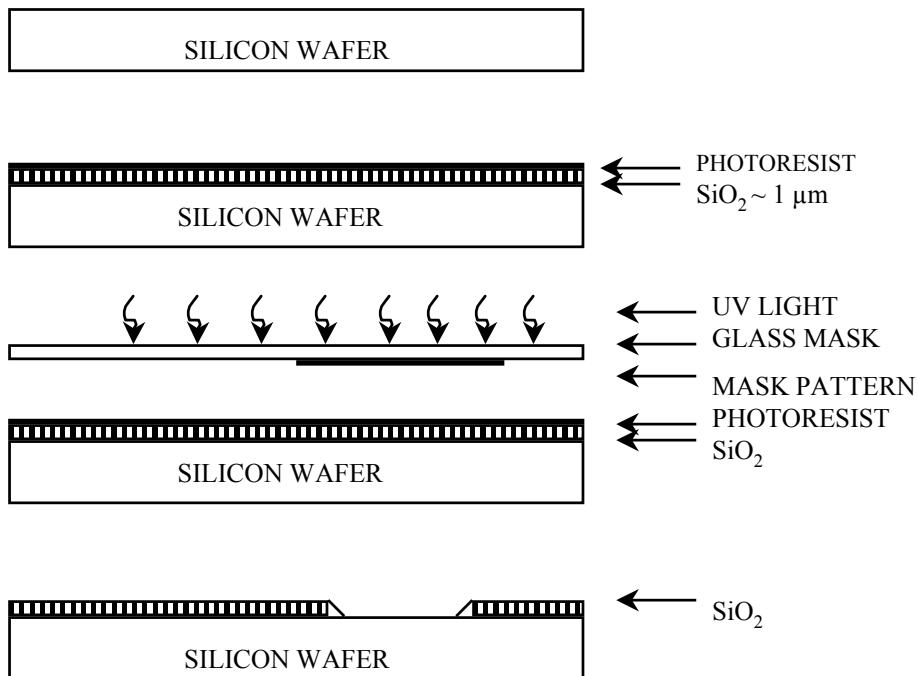
# BiCMOS Process

- CMOS based BiCMOS  
(driven from a CMOS processing base)

- Digital BiCMOS circuits tend to be CMOS-intensive because of power dissipation limitations(e.g. RAMs, uPs, gate arrays,..., etc.)  
=> highest possible CMOS performance
- Analog BiCMOS circuits are most often combined with large digital circuit  
=> results in CMOS-oriented
- Extra steps required for BJT fabrication (e.g. isolation structure) have been introduced with only minimal changes to the actual CMOS transistor fabrication sequence

- Process commonality between the bipolar and CMOS flows has been adopted whenever possible

# Device Patterning



## Photoresists

NEG - first historically

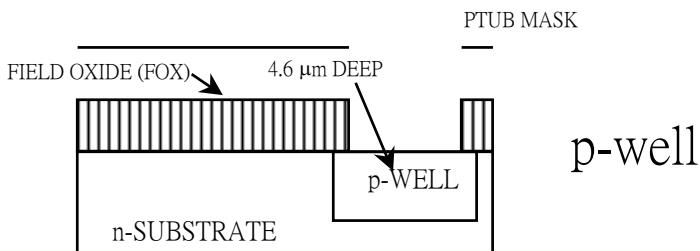
POS - better for dimensions  $< 2.5\mu\text{m}$

NEG - insoluble where exposed

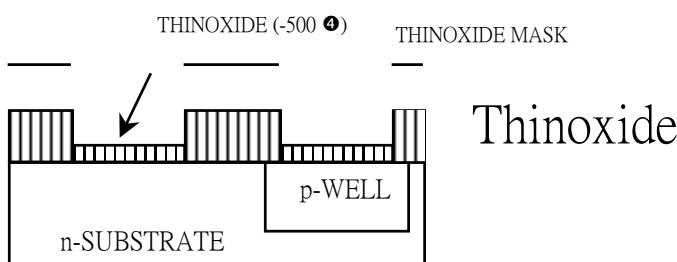
POS - soluble where exposed

# CMOS P-well Process Flow

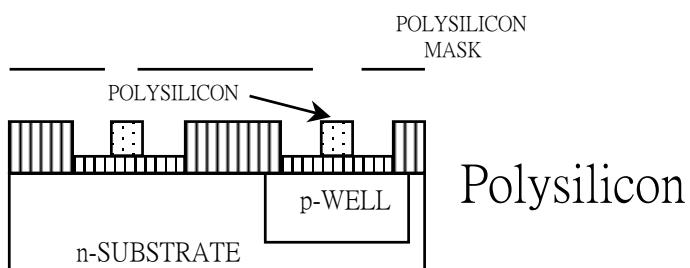
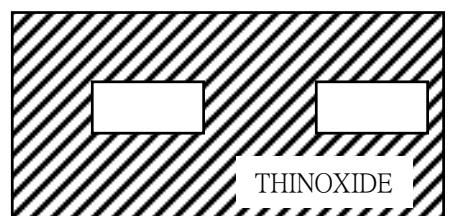
Cross section of physical structure (side View)



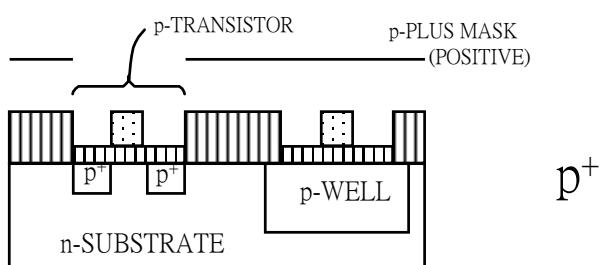
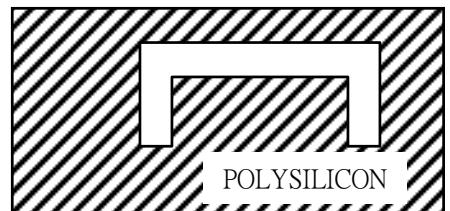
Mask  
(Top View)



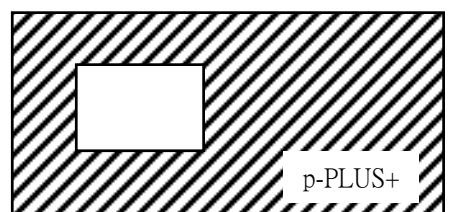
THINOXIDE MASK



POLYSILICON  
MASK

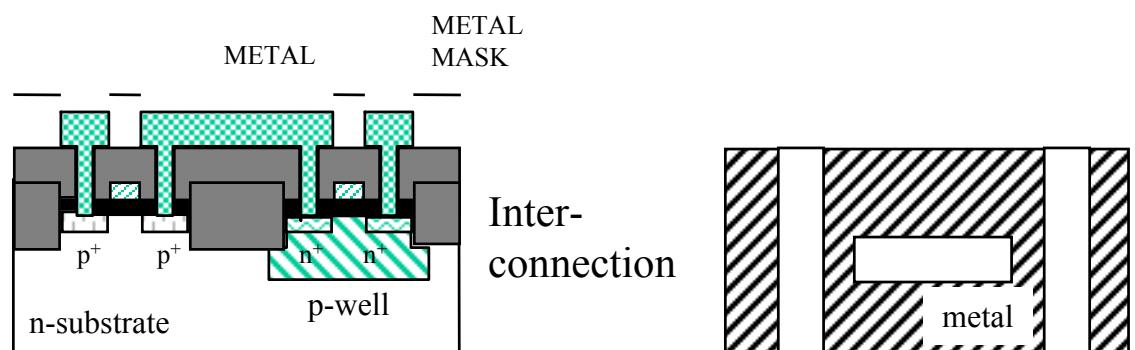
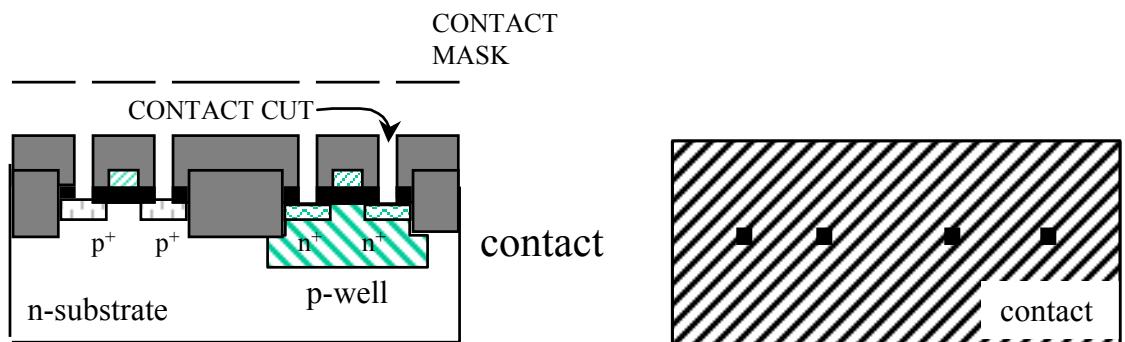
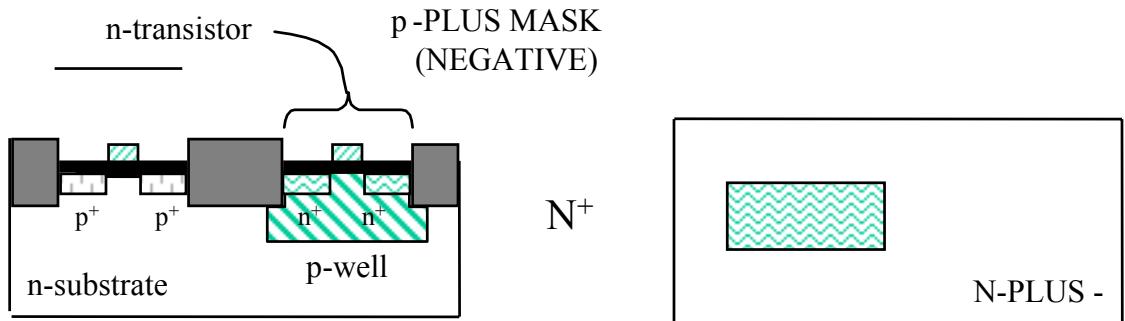


p<sup>+</sup>



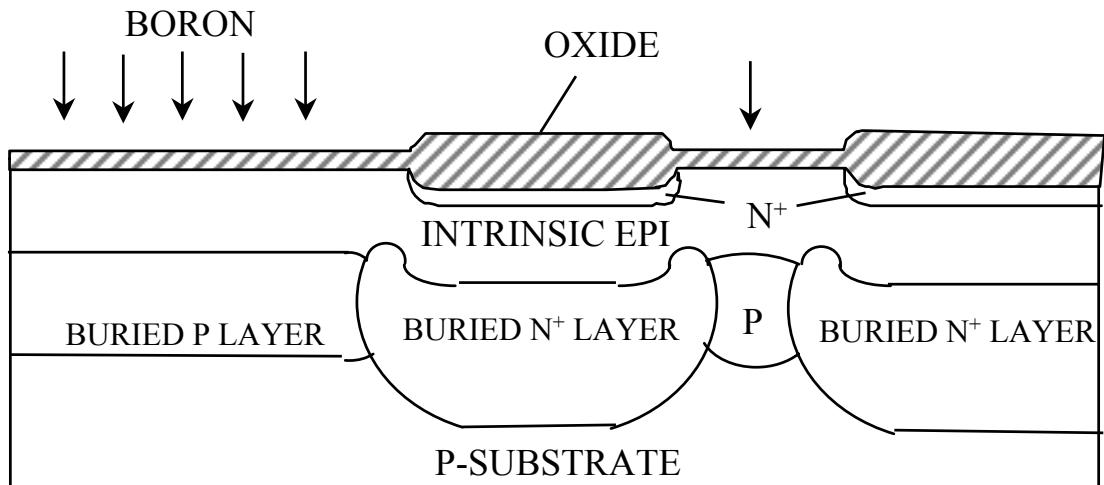
# CMOS P-well Process Flow

## (Continued)

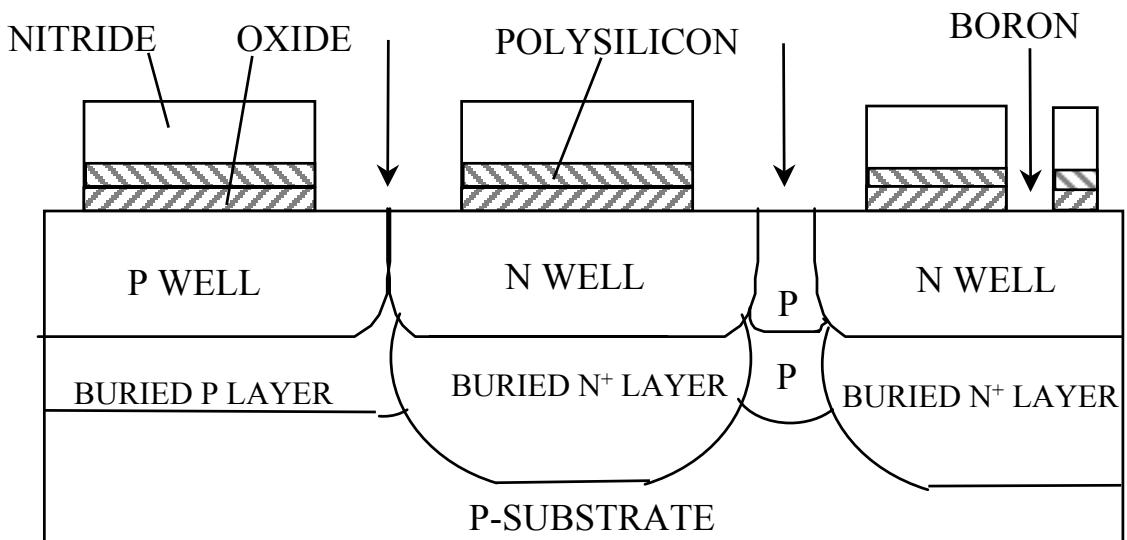


# Digital BiCMOS Process Flow

1. P-substrate
2. N<sup>+</sup> buried & oxide over N<sup>+</sup> buried
3. Self-aligned buried P<sup>+</sup>
4. Epitaxial layer with intrinsic doping

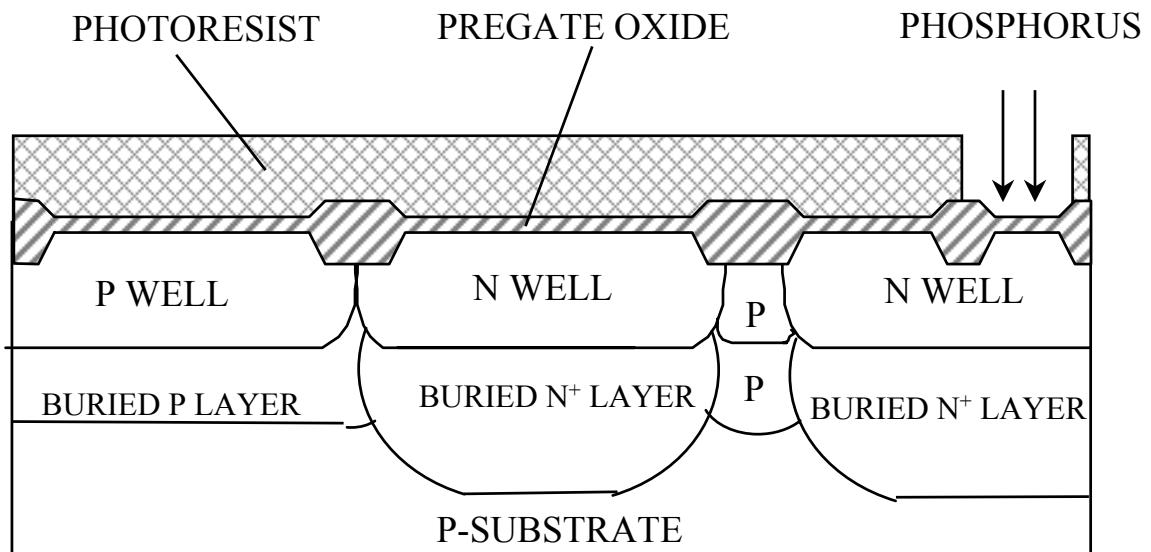


5. N-well formation & oxide over N-well
6. Self-aligned P-well
7. Active region and channel stop formation

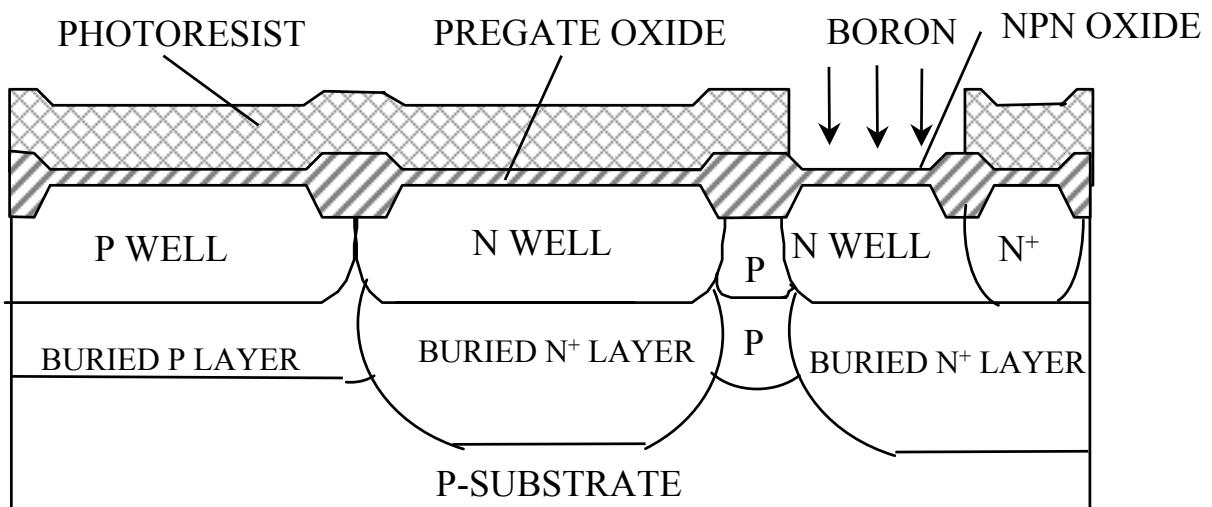


# Digital BiCMOS Process Flow(Cont.)

## 8. N<sup>+</sup> collector to deep buried N<sup>+</sup> layer

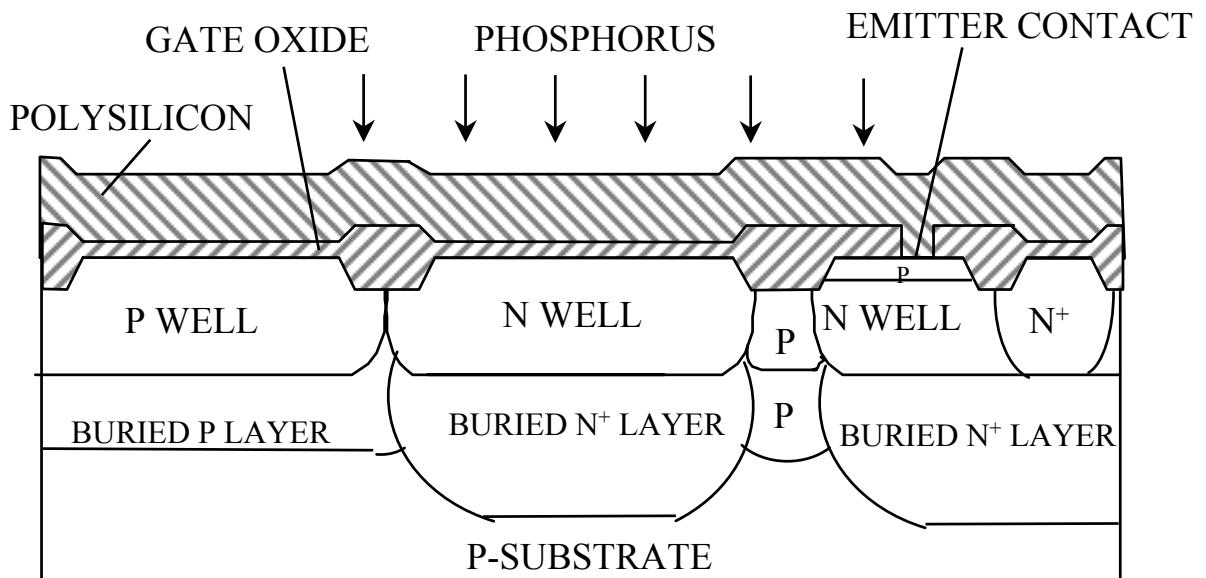


## 9. P-base and P-type resistor

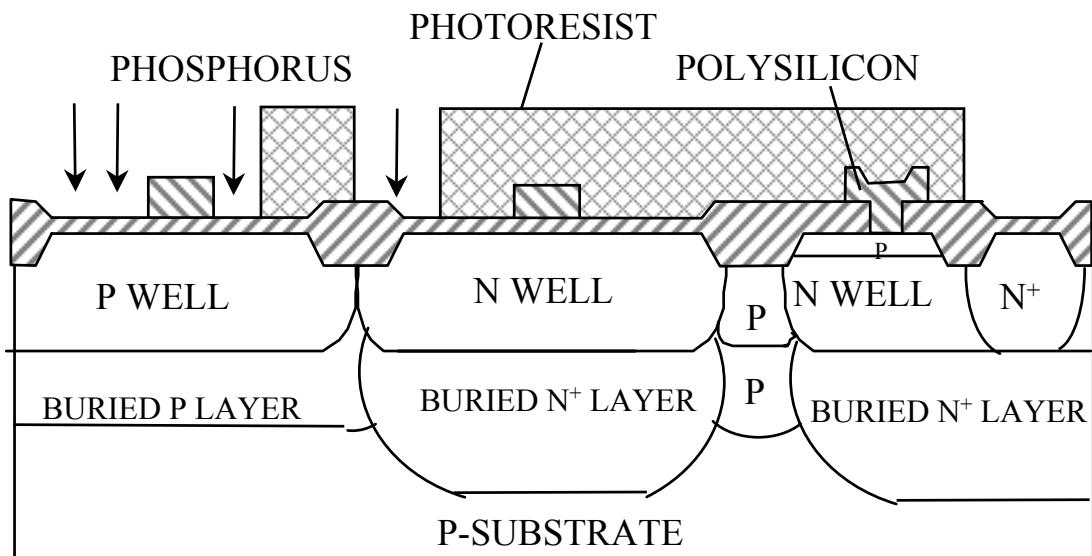


# Digital BiCMOS Process Flow(Cont.)

10. Poly emitter & N<sup>+</sup> implant into poly emitter to form diffused emitter junction

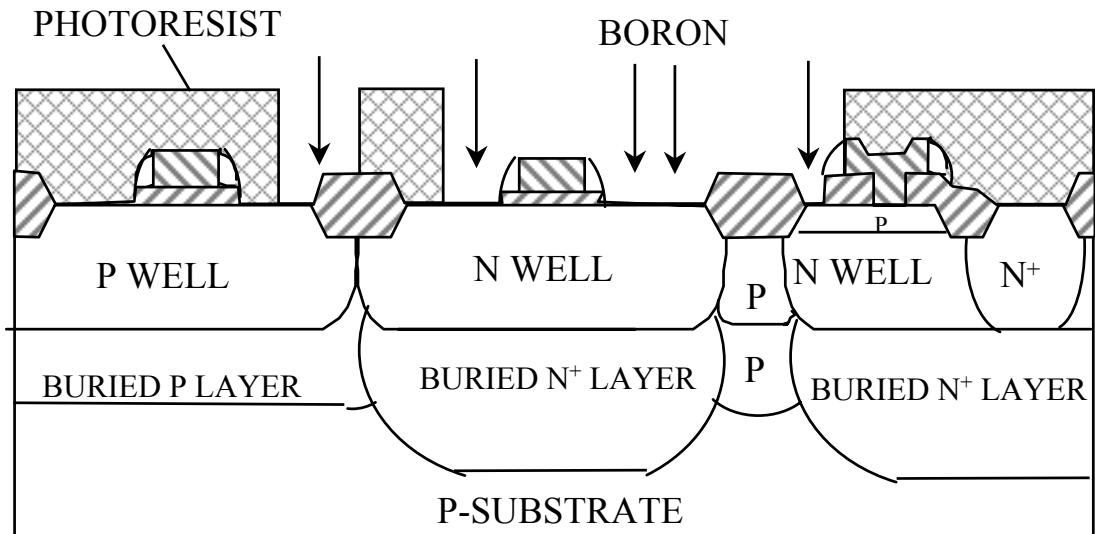


11. Gate & LDD formation



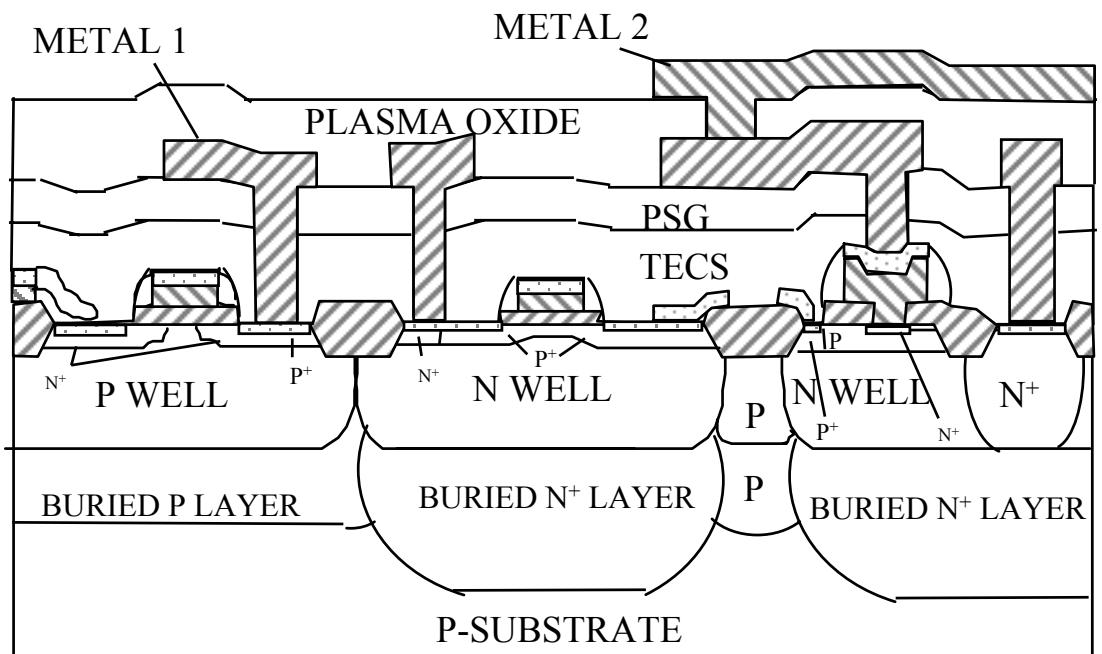
# Digital BiCMOS Process Flow(Cont.)

## 12. N<sup>+</sup> & P<sup>+</sup> S/D implant



## 13. Interconnection: silicide, contact, metal

## 14. Passivation



# Analog BiCMOS Process Components

- BJT components
  - isolated structure with
    - a. low collector resistance
      - required for high current operation
    - b. high Early voltage
      - high output resistance
  - adding PNP will result in high cost and increase process complexity
- CMOS components
  - minimum channel length of 2-3  $\mu\text{m}$  is preferred for required high output resistance
- Passive components
  - capacitors
    - poly-poly capacitors show low TC & VC, and is used to reduce parasitic effects
  - resistors
    - poly resistor & thin film resistor are used to reduce TC & VC
- Component matching                  BJT > CMOS
- Component noise                  BJT < PMOS < NMOS

# CMOS I-V Characteristics

(Example: NMOS)

- Three regions

1. Cutoff region (digital circuit)  
Subthreshold region (analog circuit)      }  $V_{GS} < V_{TH}$
2. Nonsaturation region:  $V_{GS} > V_{TH}$ ,  $V_{GD} > V_{TH}$   
(also called linear or triode region)
3. Saturation region:  $V_{GS} > V_{TH}$ ,  $V_{GD} < V_{TH}$

- Current equations for the above three regions

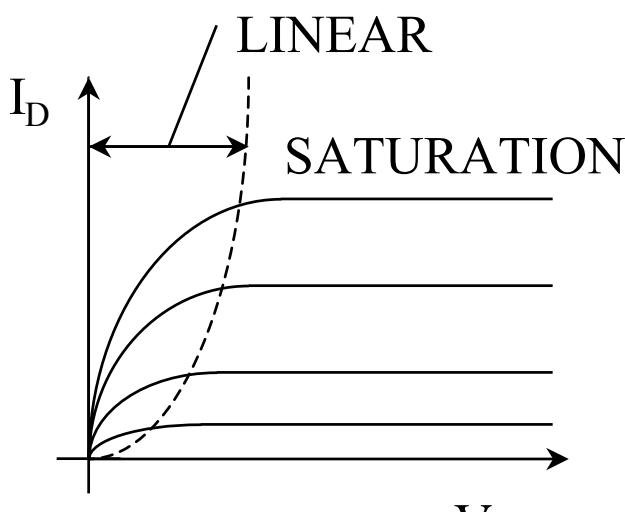
1.  $\cong 0$  (very small)

2.  $\mu_n Cox \frac{W}{L} (V_{GS} - V_{TH}) V_{DS} - \frac{V_{DS}^2}{2}$

3.  $\frac{\mu_n Cox}{2} \frac{W}{L} (V_{GS} - V_{TH})^2 (1 + \lambda V_{DS})$

where  $V_{TH} = V_{TO} + \gamma (\sqrt{2\phi_F + V_{SB}} - \sqrt{2\phi_F})$

$$\gamma = \sqrt{\frac{2q\epsilon N_A}{Cox}}, \quad \lambda = \frac{dX_d/dV_{DS}}{L_{eff}}$$



$V_{DS}$

# BJT I-V Characteristics

(Example: NPN)

- Regions:
  1. Cutoff region:  $V_{BE} < 0, V_{BC} < 0$
  2. Saturation region:  $V_{BE} > 0, V_{BC} < 0$
  3. Forward active region:  $V_{BE} > 0, V_{BC} < 0$
  4. Reverse active region:  $V_{BE} < 0, V_{BC} > 0$
- Current equation of the forward active region

$$I_C = I_S \left[ \exp\left(\frac{V_{BE}}{V_t}\right) \right] \left( 1 + \frac{V_{CE}}{V_A} \right)$$

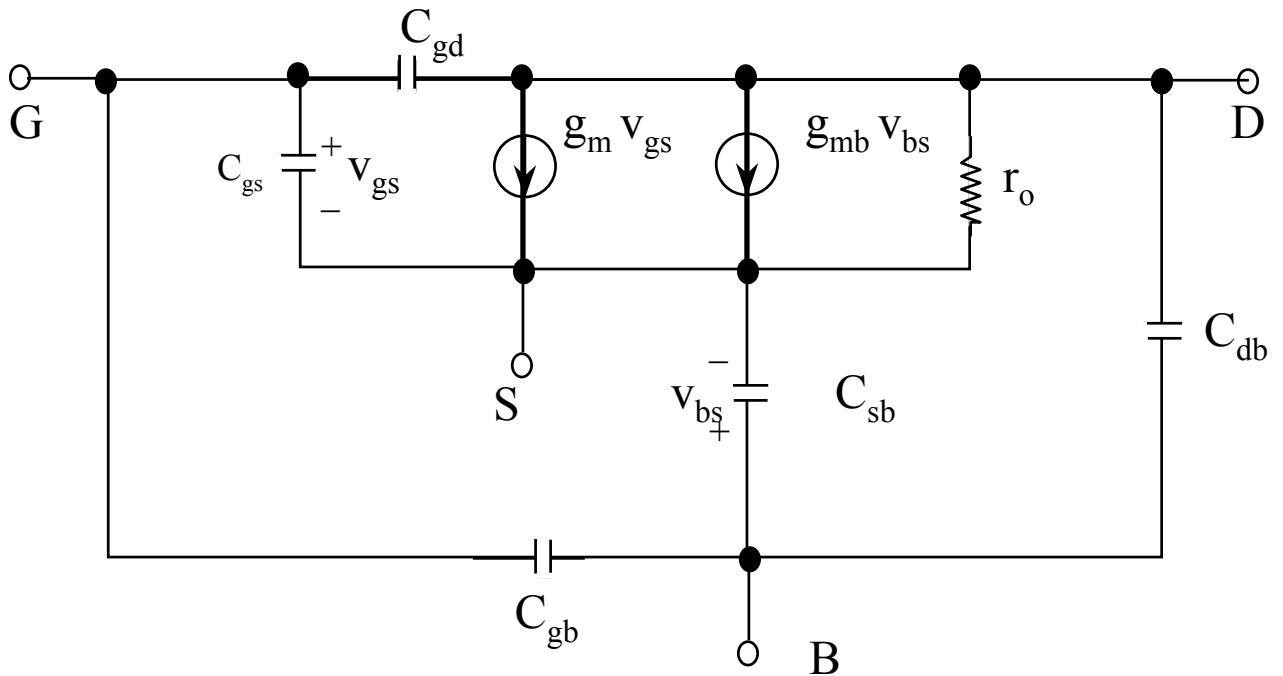
where  $I_B = \frac{I_C}{\beta_F}$ ,  $I_S = \frac{qAD_n ni^2}{Q_B}$

$$V_t = \frac{KT}{q}, \quad V_A = -W_B \left( \frac{dW_B}{dV_{CE}} \right)^{-1}$$

# CMOS Small Signal Models

(NMOS-saturation region)

- $g_m = \frac{d I_D}{d V_{GS}} \approx \sqrt{2 \mu_n C_{ox} (W/L) I_D}$
- $r_o = \left( \frac{d I_D}{d V_{DS}} \right)^{-1} = \frac{1}{\lambda I_D}$
- $g_{mb} = \frac{d I_D}{d V_{BS}} = \frac{\gamma}{2\sqrt{2\Phi_F + V_{SB}}} g_m$
- $C_{gs} \approx \frac{2}{3} WLC_{ox} + C_{gso}$ ;  $C_{gso}$  is gate-source overlap capacitance
- $C_{gd} \approx C_{gdo}$  (gate-drain overlap capacitance)
- $C_{sb}, C_{db}$  : junction capacitances



# BJT Small Signal Model

(NPN-forward active region)

$$g_m = \frac{I_C}{V_t}$$

$$r_o = \frac{I_C}{V_A}$$

$$r_\mu = \left( \frac{d I_B}{d V_{CB}} \right)^{-1} = K \beta_o r_o \quad (\text{typically, } 1 < K < 10)$$

$$C_b = \frac{d Q_B}{d V_{BE}} = \Delta_F g_m; \text{ where } \Delta_F = \frac{W_B^2}{D_n}$$

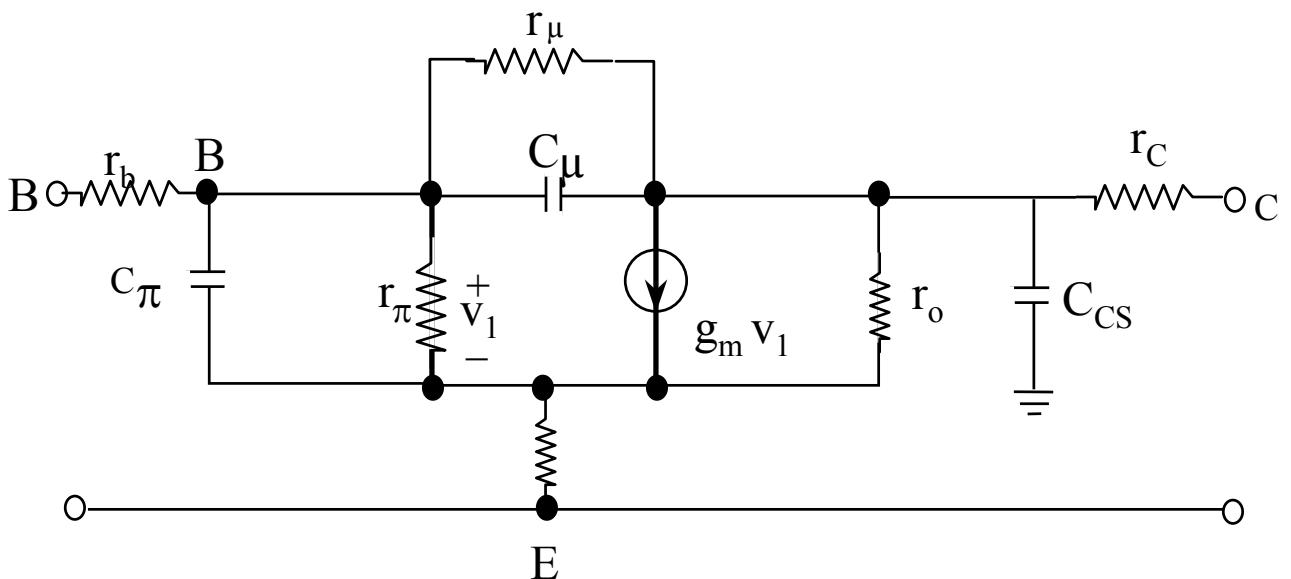
$C_{je}$ : base-emitter junction capacitance

$C_\mu$  : collector-base junction capacitance

$C_{cs}$ : collector-substrate junction capacitance

$r_b$ : ohmic resistance from base terminal to internal base

$r_c$ ,  $r_{ex}$ : collector and emitter ohmic resistances



# Comparison of BJT & MOSFET Devices

(General case)

- Transconductance  
BJT > MOSFET
- Intrinsic gain  
BJT > MOSFET
- Frequency response  
BJT > MOSFET
- Input offset voltage for differential amplifier  
MOSFET > BJT
- Noise  
MMOS > PMOS > BJT
- Input impedance  
MOSFET > BJT
- Back-bias effect (i.e. body effect)  
only MOSFET
- Switch  
MOSFET is a voltage switch.  
BJT is a current switch.

# Transconductance

## ● MOSFET

$$I_{DS} = \frac{\mu C_{ox}}{2} \frac{W}{L} (V_{GS} - V_{TH})^2$$

$$g_m = \frac{dI_{DS}}{dV_{GS}} = \sqrt{2 \mu C_{ox} \frac{W}{L} I_{DS}}$$

1. Process dependent
2. Size dependent
3. Varies as  $\sqrt{I_{DS}}$

## ● BJT

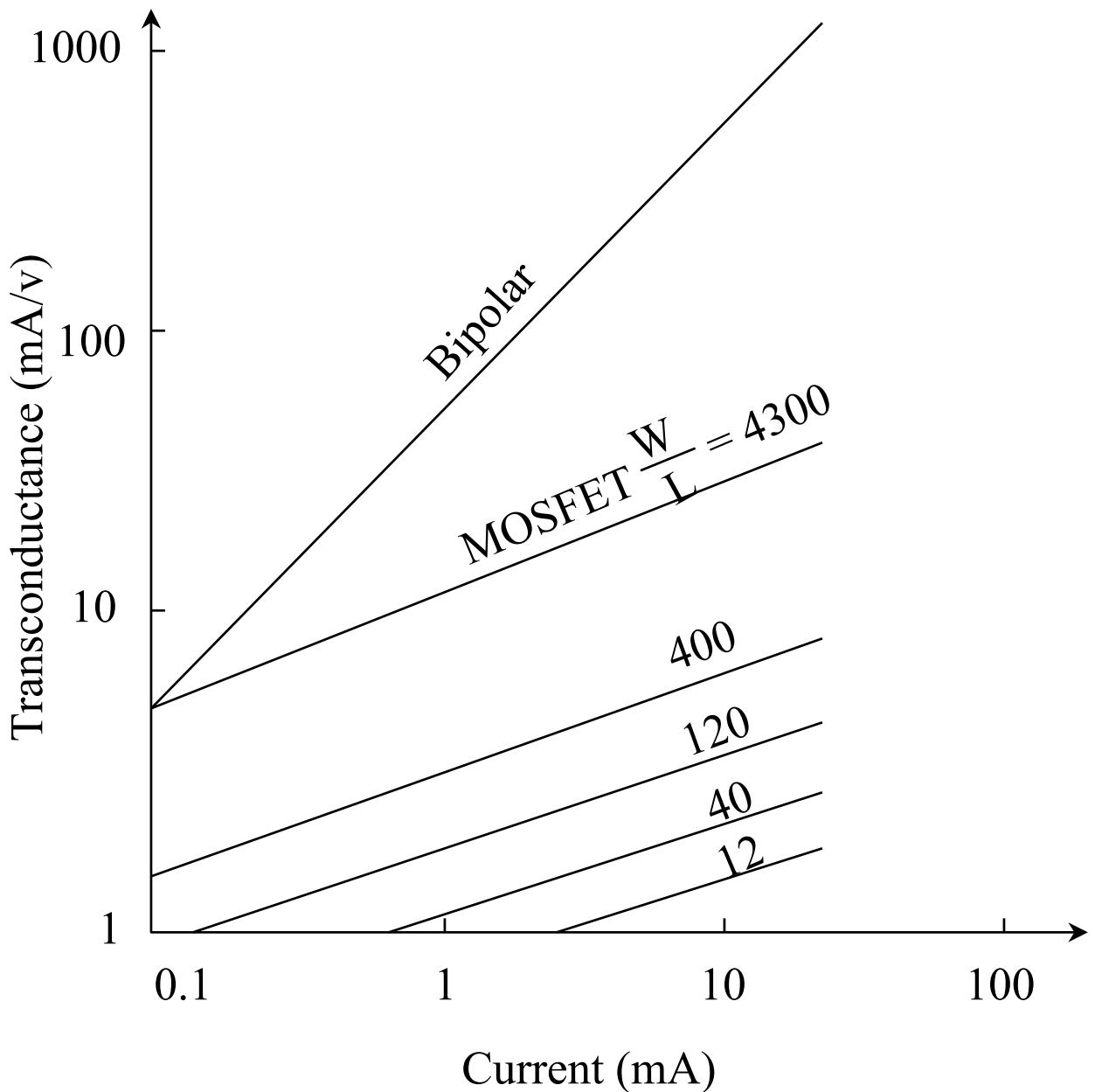
$$I_C = I_S \exp\left(\frac{V_{BE}}{V_t}\right); \quad V_t = \frac{kT}{q}$$

$$g_m = \frac{dI_C}{dV_{BE}} = \frac{I_C}{V_t}$$

1. Process independent
2. Size independent
3. Varies as  $I_C$

# Comparision of Transconductance vs. Current between MOSEETs and BJTs

- $V_t = \frac{KT}{q} = 25.9 \text{ mv}$
- $\frac{\mu C_{ox}}{2} = 10 \mu \text{A} / \text{V}^2$



# Intrinsic Gain

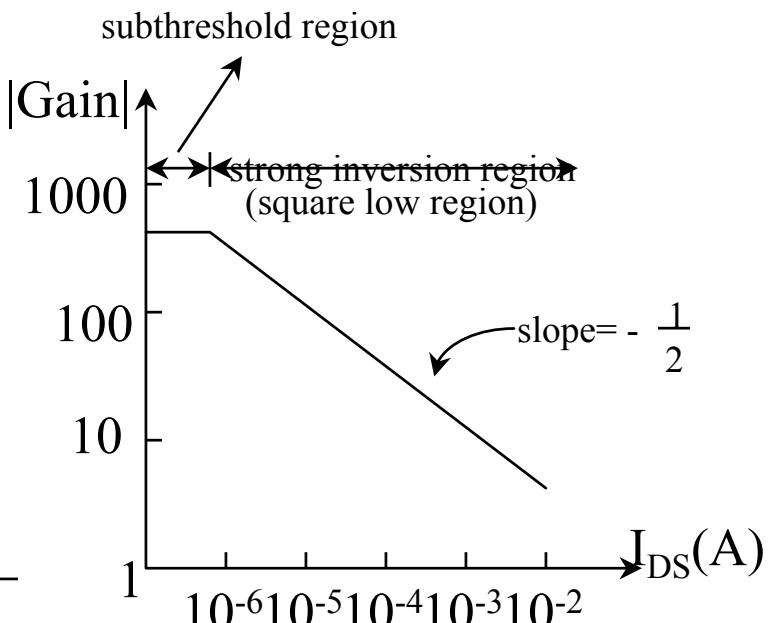
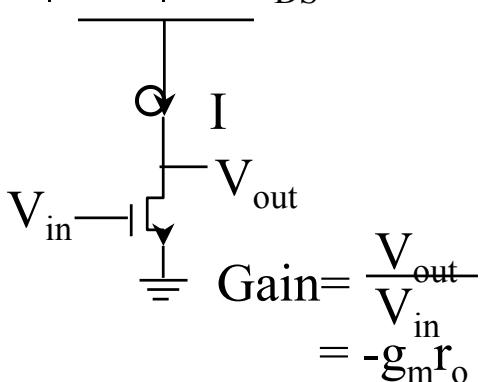
- MOS

- $g_m r_o = \sqrt{2\mu C_{ox} \frac{W}{L} I_{DS}} \frac{1}{\lambda I_{DS}}$

- $g_m r_o \propto \sqrt{L}$   
 $(\lambda \propto \frac{1}{L})$

- $g_m r_o \propto \frac{1}{\sqrt{I_{DS}}}$

- $|Gain|$  vs.  $I_{DS}$



- high input impedance
- $I \uparrow \Rightarrow$  gain  $\downarrow$  and bandwidth  $\uparrow$

- Bipolar

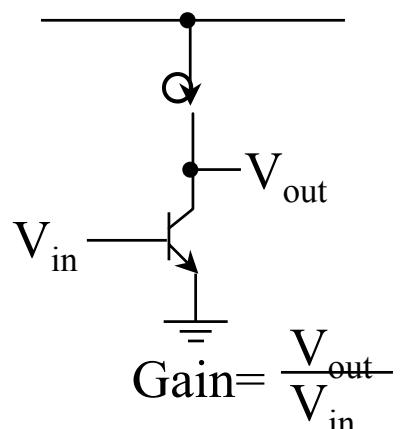
- $g_m r_o = \frac{V_A}{V_T} = \text{const. } (= \frac{1}{\eta})$

- Typical case

$V_A \approx 50V$

$g_m r_o \approx 2 \times 10^3$

- low input impedance  $\approx r_\pi$



# Frequency Response

## ● MOS

$$\omega_T = \frac{g_m}{C_{gs}} \approx \frac{\sqrt{2\mu C_{ox} \frac{W}{L} I_{DS}}}{WL C_{ox}} = \frac{\mu}{L^2} (V_{gs} - V_{th})$$

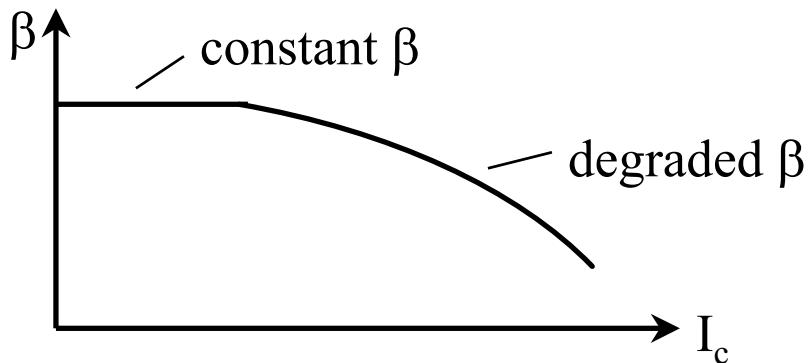
$$\omega_T \propto L^{-2}, \omega_T \propto \sqrt{I_{DS}} \propto (V_{gs} - V_{th})$$

- ↷ In terms of  $I_{DS}$ , high  $\omega_T$  is incompatible with high gain  
 $(g_m I_0 \propto \sqrt{L} \quad \text{but} \quad g_m I_0 \propto \frac{1}{\sqrt{I_{DS}}})$

## ● Bipolar

$$\omega_T = \frac{g_m}{C_\pi + C_\mu} \propto I_c \quad \text{where} \quad g_m = \frac{I_c}{V_T}$$

- ↷ For BJT,  $\beta$  is decreased at high current



# Input Offset Voltage of Differential Amp.

- Amp. with resistor load

— BJT

$$V_{OS} = \frac{KT}{q} \left[ -\frac{\cancel{R}}{R} - \frac{\cancel{A_E}}{A_E} - \frac{\cancel{Q_B}}{Q_B} \right]$$

where

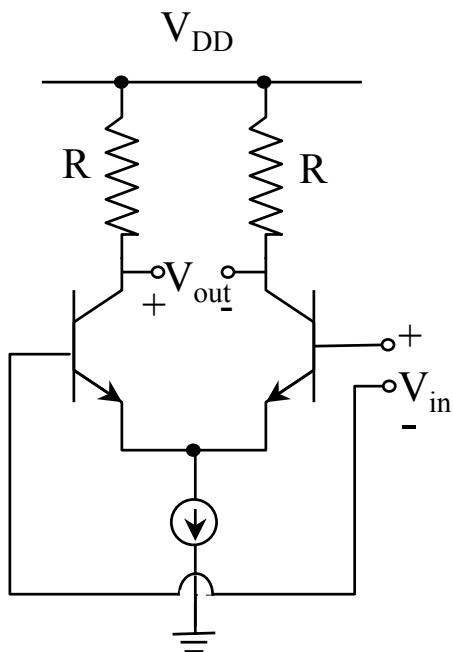
$\frac{KT}{q}$  is thermal voltage

R is load resistor

$A_E$  is emitter area

$Q_B$  is base Gummel number

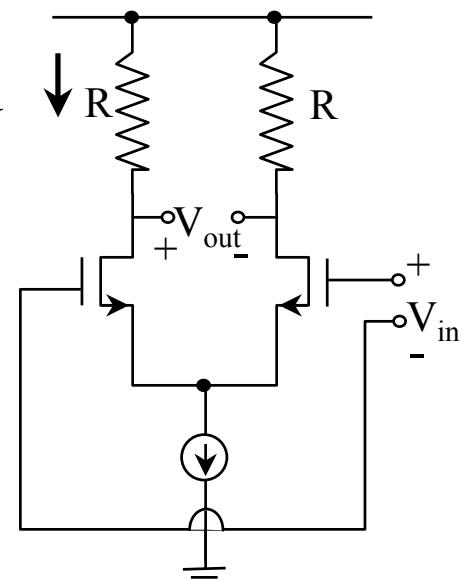
$\cancel{}$  represents the mismatch between the parameters



— MOSFET

$$V_{OS} = \cancel{V_{TH}} + \frac{V_{GS} - V_{TH}}{2} \left[ -\frac{\cancel{R}}{R} - \frac{\cancel{(W/L)}}{W/L} \right] V_{DD}$$

$$\frac{V_{GS} - V_{TH}}{2} \downarrow \Rightarrow V_{OS} \downarrow \text{and speed}$$



- $V_{OS(\text{MOSFET})} \gg V_{OS(\text{BJT})}$

$\cancel{V_{TH}}$  only in MOSFET

$\frac{V_{GS} - V_{TH}}{2}$  is about the order of 1V

$\frac{KT}{q}$  is about 25.9mV

$$\Rightarrow \begin{cases} V_{OS(\text{BJT})} \sim 1\text{mV} \\ V_{OS(\text{MOSFET})} \sim 5-10\text{mV} \end{cases}$$